

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.:	<b>10/791,926</b>	Examiner:	<b>Emmanuel S. Luk</b>
Inventor:	<b>Hong Hocheng and Chin Chung Nien</b>		
Filed:	<b>March 2, 2004</b>	Art Unit:	<b>1722</b>
Title:	<b>Nano-Imprint System With Mold Deformation Detector And Method Of Monitoring The Same</b>		

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

AMENDMENT A

In response to the Office Action mailed **03/12/2007**, please amend the above-identified application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper.

**Remarks** begin on page 8 of this paper.